and are removed from the device prior to device operation.

Please replace the paragraph beginning at page 11, line 3, with the following rewritten paragraph:

Figure 3 is a schematic representation of one element of a micromirror array illustrating the circuitry driving a micromirror. In Figure 3, data is written to the micromirror element through bit line 302. Word line 304 is active when the element is written to causing the switch, shown as pass transistor 306 to turn on and allowing the bit line driver to charge the memory capacitor 308. When a logic high signal is stored on the memory capacitor 308, the mirror transistor 310 is turned on grounding the mirror structure 312.

Please replace the abstract of the disclosure with the following rewritten paragraph:

A capacitively coupled microelectromechanical device comprising: a semiconductor substrate; a member operable to deflect to either of at least two states; and a switch for selectively connecting the member to a voltage signal. When a logic high signal is stored on ~~the~~ memory capacitor, mirror transistor is turned on, grounding the mirror structure. When a logic low signal is stored on the memory capacitor, the mirror transistor is turned off, allowing the mirror to float electrically. Mirrors that are tied to a voltage potential, which typically are grounded, are affected by a reset pulse and rotate away from their landed position. When the mirrors have rotated to the opposite side, a bias signal is applied to hold the repositioned mirror in place in the opposite state. Mirrors that electrically are floating do not experience the forces generated by the reset voltage and remain in their previous state.

In the claims:

Please amend Claims 1, 14, 18, 19, 30, and 31 as follows:

1. (amended) A micromechanical device comprising:

a semiconductor substrate;

at least one member operable to deflect about a torsion axis to either of at least two states;

a switch associated with each said at least one member for selectively connecting